

中文索引

CHINESE INDEX

cDNA 晶片 complementary DNA microarray 1118
DNA 晶片 DNA chip 1117-1120, 1153-1155, 1219-1220
UV 厚膜光阻 UV thick film resist 172-173, 184
X 光 LIGA X-ray LIGA 143, 145-146, 150-151, 169, 172, 184, 194
X 光光罩 X-ray mask 143, 151, 153, 155-156, 162, 228, 431
X 光深刻 deep X-ray lithography 144-146, 149-152, 154-155, 157, 159-160, 162, 165-166, 168-169, 171, 434-436, 441-442
X 光微影 X-ray lithography 43-44, 47, 145
X 光繞射儀 X ray diffractometer (XRD) 403

二劃

二次離子質譜儀 secondary ion mass spectroscopy (SIMS) 401, 407-409
人工鼻氣體感測器 artificial nose gas sensor 1224

三劃

三維封裝 3D packaging 819

四劃

介面技術 interface technology 705, 1205
元件行為階層 device behavior level 1052, 1056, 1102
元件物理階層 device physical level 1052-1053, 1099, 1102
元件封裝 device packing 497-498, 769-770, 789-790, 960, 1070, 1185, 1196-1197
內部掃描 internal scanning 949
內應力 internal stress 80, 150, 152-153, 227, 232-233, 237, 239-240, 243, 489, 562, 794, 866, 1038
分子電子 molecular electronics 1242-1243
切割 dicing saw 210, 242, 280, 335, 376, 387, 392, 400, 436, 476, 483-484, 487, 499, 684, 780, 812, 814, 820, 822, 824, 1054, 1101, 1197, 1253
化學氣相沉積法 chemical vapor deposition (CVD) 28, 31, 51-52, 56, 64-71, 82, 92, 101, 103-105, 111, 117, 125, 221, 227, 256, 269, 282, 337-338, 341, 343-360, 376, 462, 562, 643, 683, 788, 864, 1169, 1247, 1249
化學機械研磨 chemical mechanical polishing (CMP) 51-53, 76, 107-108, 116, 338, 347, 828, 1096
反應限制區域 reaction-limit region 337, 349
反應離子蝕刻 reactive ion etching (RIE) 54-55, 61, 78, 104-105, 108, 117, 125-126, 144, 156, 172, 177, 181, 203, 209-212, 215, 224, 284, 296, 302, 306, 329, 331, 351, 354-355, 418, 423, 425, 428, 442, 477, 525, 643, 835, 1128, 1186, 1249
毛細管微成形 micromolding in capillaries (MIMIC) 144, 294, 298-301, 303, 565

五劃

- 凸角攻擊 corner attack 86-87
- 加速度計 accelerometer 4, 77, 97, 101, 105, 116-117, 125, 141, 227, 273, 361, 471, 505, 614, 705-706, 777, 797, 816, 828-833, 836, 1022, 1034, 1036, 1038, 1057, 1081, 1213, 1226, 1228-1229
- 功能性材料 functional material 361
- 功率流 power flow 1084, 1091
- 可靠度 reliability 14, 36, 56, 62-63, 98, 102-103, 110, 113, 116, 118, 129, 345, 397, 401, 446, 477, 501-503, 506-507, 512, 518, 565, 611-612, 614, 627, 631, 659, 667, 813, 817, 836, 1023-1029, 1033-1034, 1036, 1113, 1125, 1130, 1172-1173, 1176, 1181, 1197, 1201, 1206
- 可靠度工程試驗 reliability engineering test 1023, 1028
- 可靠度決定試驗 reliability determination test 1028
- 可變電容 tunable capacitor 119, 121, 510, 630, 787, 789, 835, 1174-1176, 1178-1181
- 四點探針 four point probe 11, 841
- 失效模式 failure mode 1022-1023, 1029-1030, 1032-1034, 1036, 1039
- 失效模式與效應分析 failure mode and effects analysis (FMEA) 1033-1034
- 巨觀模型 marco model 1052, 1056, 1084-1085, 1087-1090, 1092, 1102
- 打線 wire bond 77, 107, 393-394, 396, 398-399, 468, 502, 674, 770, 777, 783, 790, 808, 813, 819, 822, 1030, 1038, 1169, 1214
- 打線機(焊線機) 392, 822
- 生物感測器 biosensor 132, 298, 361, 1005-1006, 1221, 1223
- 皮托管 Pitot tube 532, 542
- 示差掃描熱量分析儀 differential scanning calorimeter (DSC) 277, 401, 896-897

六劃

- 光分解挖除 photoablation 187-190
- 光束均勻器 homogenizer 191-192
- 光刻技術 photolithography 143-144, 162, 170, 172, 203, 227, 294, 297, 299-300, 351, 441, 1218
- 光阻 photoresist 3, 35-36, 38-44, 48-51, 54, 56, 77, 82, 99, 104-105, 107, 125, 141, 144, 146, 149-153, 156-165, 172-184, 192, 194, 202-203, 206, 210, 215, 217, 220-222, 224, 226-228, 230-233, 235-237, 242-243, 269, 272-274, 276, 279-282, 284, 286, 290, 294, 297, 301, 306, 331, 354-356, 361, 418-423, 425-429, 434, 440-444, 672, 785, 801-802, 815, 818, 1095, 1121, 1133, 1146, 1171, 1247, 1250
- 光柵式光閥元件 grating light valve 621, 1108, 1110-1111
- 光柵掃描 raster scan 45, 425
- 光衰減器 optical attenuator 127, 191, 630, 640, 670, 1110-1112
- 光感測器 photodetector 570-573, 575-576, 578, 580-581, 962, 997-1000, 1250
- 光罩工具 layout tool 1055, 1098
- 光電式感測器 photoelectric detector 581
- 光學微影 optical lithography 33, 36, 43, 46-47, 294, 423, 1191, 1247
- 光纖光柵 fiber grating 185, 208-209
- 全像干涉術 holographic interferometry 984-985, 988, 995

共形光罩 conformal mask 441
 共振器 resonator 116, 119, 125, 127, 334, 355, 385, 616, 621, 630, 644, 683, 1022, 1057, 1183-1188, 1190-1195, 1198-1201, 1224, 1243-1245, 1247, 1249, 1259-1261
 共晶接合法 eutectic bonding 790, 807-808
 印刷電路板 printed circuit board (PCB) 120, 272, 393-394, 398, 490, 833, 974, 1092, 1213-1214
 同步輻射 synchrotron radiation 3, 77, 143-144, 146-150, 156, 159-161, 165-168, 170-172, 441
 合金電鑄 alloy electroforming 227, 235, 239-240
 回授控制 feedback control 676, 705-706, 733, 735, 737, 742, 745-746, 754-755, 921
 多重物理領域 multi-physics 1052, 1056
 收縮 shrinkage 54, 111-112, 247-249, 254, 306, 308, 340, 379, 397, 401, 651, 797, 871, 873, 913, 1030
 有限元素法 finite element method 483, 777, 884, 958, 1050-1051, 1053-1054, 1057-1058, 1099-1100, 1255
 次微米解析度 sub-micron resolution 145
 米勒指標 Miller index 83, 324
 自組裝單層膜 self-assembled monolayer (SAM) 104, 294-297, 574, 946-948, 952, 1120-1121

七劃

低溫鍍膜材料與製程 low-temperature process 271
 低壓化學氣相沉積 low pressure chemical vapor deposition (LPCVD) 66-70, 82, 92, 101, 103, 105, 111, 117, 269, 337-338, 341, 343-354, 358-359, 562, 643, 788
 吸收係數 absorption coefficient 40, 44, 153, 155, 165, 189, 198, 572, 578
 形狀記憶合金 shape memory alloy 4, 291, 357, 377-378, 382, 390-391, 774, 1125, 1127, 1131
 快速成型法 rapid prototyping (RP) 24, 31, 255, 285, 350, 397, 447, 574, 588, 847-848, 908-909, 916
 快速熱氧化法 rapid thermal oxidation (RTO) 32
 快速熱製程 rapid thermal process (RTP) 7, 28-32
 折射式微鏡片 refractive microlens 417-418, 428
 投射影像 aerial image 36-38, 40-41
 投射範圍 projected range 24
 材料庫 material database 1054, 1101-1102
 步進式微致動器 scratch drive actuator (SDA) 619, 650-651, 654-657
 系統封裝 system packaging 336, 769-770
 系統特性方程式 system characteristic equation 746-747, 754
 系統階層 system level 770, 1052, 1056, 1075, 1077-1079, 1082-1085, 1091-1093, 1098, 1102
 角落補償 corner compensation 87, 92, 94

八劃

固態高分子電解質 solid polymer electrolyte (SPE) 27, 370-371
 固態粒子感測器 solid-state particle detector 581-583
 奈米光學 nano optics 918, 931
 奈米夾子 nanotweezer 1253
 奈米微影 nano-lithography 209, 936, 946, 1244

- 奈米碳管 carbon nanotube 132, 566, 887, 1243, 1253-1254
- 底切 undercut 48-49, 82, 86, 92, 94, 119, 201, 212, 215, 441, 1080, 1095-1096
- 拋物速率係數 parabolic rate coefficient 18
- 明膠 gelatin 145, 271, 274-282
- 物理沉積 physical deposition 56
- 直接接合法 direct bonding 790-791
- 矽基板 silicon substrate 26, 54, 220-222, 224, 362, 390, 454, 477, 576, 612, 620-621, 647, 656, 781, 795, 851, 1050, 1135
- 矽深蝕刻 silicon deep etching 114, 183, 214, 217, 322
- 矽微加工 silicon micromachining 75, 141, 143-144, 211, 246, 383, 467-469, 630, 641-643, 671-672, 676-677, 959, 1179
- 矽微條感測器 silicon microstrip detector (SMD) 555, 583, 585-586
- 矽漂移腔感測器 silicon drift chamber (SDC) 583-584
- 矽膠 silicone 145, 251, 271, 284-285, 296, 336, 500, 786, 1038, 1123, 1132
- 表面波 surface wave 947, 949-951, 1002, 1191, 1213
- 表面粗度儀 alpha-step profilometer 844
- 表面電漿子共振技術 surface plasmon resonance (SPR) 996, 1000-1002, 1004-1006, 1223
- 表面聲波 surface acoustic wave 362, 368, 387, 503, 946, 1161, 1184, 1191, 1224, 1249
- 表面聲波顯微鏡 surface acoustic microscope (SAM) 294, 296-297, 574, 946-948, 952, 1120-1121
- 表面體積比 surface-to-volume ratio 344
- 近接效應 proximity effect 1061-1062, 1247
- 近場光學 near-field optics 209, 450, 918, 920-926, 928-932, 934, 936, 938-946, 953, 956-958, 1260
- 近場掃描光學顯微術 near-field scanning optical microscopy 918
- 陀螺儀 gyroscopes 4, 97, 116, 273, 344, 375, 505-513, 515-519, 630, 706, 816, 836, 1022, 1037, 1087, 1203, 1209-1211, 1226-1229
- 非破壞檢測 non-destructive measurement 978
- 非晶 amorphous 27, 31, 81, 83, 110-112, 274, 294, 322, 327, 332, 338-341, 343, 349, 354-355, 379, 383, 390, 481, 485, 576, 795, 1037
- 非等向性 anisotropy 49-50, 53-55, 75, 78-80, 82-83, 85, 91-92, 98, 118-119, 125-126, 141, 211-212, 214-215, 218, 221-222, 322, 327-332, 340, 358, 459, 472, 477, 479-480, 529-530, 643-644, 648, 1135, 1247, 1249, 1252
- 非等向性蝕刻 anisotropic etching 54-55, 78-80, 82-83, 85, 91-92, 125-126, 141, 211, 215, 221, 328-331, 340, 358, 459, 477, 479, 529-530, 644, 1095, 1135, 1249, 1252
- 非等向蝕刻模擬 anisotropic etching simulation 1095-1096, 1102

九劃

- 前饋控制 feedforward control 733-734
- 垂直式梳狀致動器 vertical comb actuator (VCA) 636-639
- 封裝材料 package material 322, 392, 398, 499, 564, 778-779
- 封裝設計 package design 498, 500, 770, 777, 783, 825
- 後段後製程 post process 113
- 相位光罩 phase mask 208

相位前引控制器 phase lead controller 751-752
 相位落後控制器 phase lag controller 752-753, 755
 相移法 phase shifting technology 985, 987-989, 991, 993
 科氏力 Coriolis force 375, 508-513, 515-516, 532
 突衝 pull-in 618, 639, 651, 868, 883-884, 1059-1061
 紅外線面陣列感測元件 infrared focal plane array (IRFPA) 530
 耐久性試驗 durability test 1025, 1036
 背面蝕刻 back-side etching 3, 118, 143, 343, 370
 致動材料 actuator material 322, 362, 377-378, 380, 383, 391
 致動器封裝 actuator package 782
 計算模型 computational model 1050, 1056, 1102
 面型微加工 surface micromachining 75-78, 97-99, 101-106, 110-112, 116, 211, 281, 322, 329, 336-337, 344-346, 348, 350-352, 355-359, 374, 530, 555, 565, 618-621, 632, 672, 677, 759, 868, 1077, 1094, 1169, 1176, 1247
 音阻抗 acoustic impedance 562, 946-947

十劃

原子力顯微術 atomic force microscopy 449-451, 887, 893, 895-896, 901-902, 916-917
 射出成形 injection molding 204, 224, 226, 246, 248, 251, 256, 398, 426, 428-429, 434-435, 477, 814, 825
 射頻微機電系統 RF-MEMS 393, 1160, 1164, 1201
 氣泡室 bubble chamber 581-582
 氣相沉積 vapor-deposited 28, 31, 56, 64-65, 67-68, 82, 101, 103-104, 108, 111, 117, 125, 155, 282, 337-338, 346, 355-356, 358-360, 380, 455, 462, 586, 683, 788, 807, 809, 864, 878, 1247, 1249
 氣動式微致動器靜 pneumatically actuator
 消失模 lost-mold 251
 紡口 spinneret 227, 252, 254, 433-436
 能量密度 fluence 38, 77, 189-191, 194-196, 198-199, 201, 203-204, 210, 385, 390-391, 614, 686, 1204, 1209, 1211
 閃爍計數器 scintillation counter 580-582
 高密度電漿化學氣相沉積 high density plasma chemical vapor deposition (HDPCVD)
 高深寬比 high aspect ratio 3, 55, 58, 64, 69-71, 76-78, 98, 101, 117, 143-145, 164, 167-169, 172-173, 177, 180, 182-185, 192, 196, 203, 210-212, 214-215, 218, 224-225, 227-228, 230-233, 235, 237, 256, 262, 268, 290, 301, 306, 308, 322, 328-329, 333, 347, 354-355, 357, 359, 361, 377-378, 434-436, 442, 454, 457, 459, 516, 601, 624, 637, 640, 644-645, 674, 908-909
 高深寬比結構 high-aspect ratio microstructure 76-77, 98, 101, 169, 196, 235, 359, 361, 516, 624, 640
 高電漿密度低氣體壓力 high density low pressure (HDLP) 211-212
 胺基磺酸鎳 nickel sulfamate 180, 232, 946, 1244

十一劃

參數化光罩 parametrized layout 1055, 1098
 基因表現 gene expression 1119-1120, 1124, 1157-1159
 常壓化學氣相沉積 atmospheric pressure chemical vapor deposition (APCVD) 67-68, 353-354, 359, 1247

張應力 tensile stress 111, 331, 340, 346, 390, 475, 489, 558, 561-562, 866, 868, 871-873, 878, 880, 882
 捲帶式自動接合 tape automated bonding (TAB) 394, 396-397, 399-400
 掃描式電子顯微鏡 scanning electron microscope (SEM) 19, 47, 130, 217, 221, 351, 401, 404-405, 422, 427, 445, 452, 640, 643-645, 648, 655, 853, 864, 911, 1117, 1253-1254
 掃描式顯微鏡 scanning microscope 886, 996-997, 999, 1245
 掃描近場顯微術 scanning near-field optical microscopy 450-451
 掃描穿隧顯微術 scanning tunneling microscopy 449-450, 886-887, 891, 894, 915, 917
 旋塗式玻璃 spin-on glass (SOG) 269, 346-347, 795
 焊線機 (打線機) wire bonder 394, 822
 異常共沉積 anomalous deposit 240
 粒子影像流速儀 particle image velocimeter 1006-1007, 1010, 1018, 1020, 1022
 蛋白質晶片 protein chip 1120, 1219-1220
 設計法則驗證 design rule check (DRC) 612, 1054-1055, 1097, 1099-1100, 1102
 貫穿孔 via 105, 108, 118, 129-130, 815, 817-818, 835-836
 軟式微影 soft lithography 145, 294, 307
 都卜勒振動／干涉儀 advanced vibrometer/interferometer device (AVID) 953-958, 960, 1110
 麥克風 microphone 97, 141, 273-274, 370, 376-377, 544-551, 553-562, 564-568, 570, 781, 1164, 1206, 1229
 麥克風陣列 microphone array 567-568

十二劃

傅利葉光學 Fourier optics 997
 單一電子電晶體 single electron transistor (SET) 116, 165, 470, 477, 482, 491, 720, 722, 758, 778, 913, 968, 1029, 1181, 1258-1259
 單倍率望遠鏡 1× telescope 961, 964-966, 977
 單晶矽 single crystal silicon (SCS) 3, 75, 77-84, 91, 95-96, 98, 141, 143, 172, 181, 183, 210-211, 221-223, 296, 327-329, 331, 336, 342-344, 354, 360, 450, 459, 519, 562, 826, 1095, 1178, 1189, 1245, 1250, 1254, 1256, 1259
 晶片接合技術 wafer bonding technology 3, 790, 810
 晶界 grain boundary 110-111, 327, 341, 343, 366, 406, 1038
 晶圓切割機 dicing saw machine 820
 晶圓封裝 wafer package 400, 769
 晶圓框架 wafer frame 820
 晶體結構 crystal structure 66, 166, 322-324, 327, 329, 334, 339, 352, 354, 360, 401, 525, 1245
 殘餘應力 residual stress 76, 103, 110-111, 116, 130, 143, 152, 154, 156, 158, 224, 259, 271, 331, 338, 344, 346, 349-350, 352, 358-359, 376, 384, 479, 560, 563, 619, 626, 689, 804, 810, 864, 866-867, 870-873, 877-880, 882-886, 1171
 游離式感測器 ionization detector 581
 等向性 isotropy 9, 49-51, 53-55, 75, 78-83, 85, 91-92, 98, 118-119, 125-127, 141, 152, 177, 211-212, 214-215, 217-218, 220-222, 322, 327-332, 340, 351, 358, 459, 472, 477, 479-480, 529-530, 643-644, 648, 847, 947, 1135, 1247, 1249, 1252
 等向性蝕刻 isotropic etching 54-55, 78-83, 85, 91-92, 125-127, 141, 177, 211-212, 215, 217-218, 220-222, 328-331, 340, 351, 358, 459, 477, 479, 529-530, 644, 1135, 1249, 1252

等效電路 equivalent circuit 559, 1081, 1089, 1091, 1189
 結晶 crystal 25-27, 44, 67, 83, 110-112, 143, 210, 222, 322, 327, 331, 333-334, 338-341, 343, 345, 353, 360, 379, 382, 390, 393, 403-404, 460, 678-679, 795, 823, 866, 1095, 1112-1113, 1254, 1256
 結構層 structural layer 4, 77-78, 97, 101-103, 105, 130, 176-177, 220, 269, 272, 274, 281-282, 322, 336, 343-344, 347, 350, 354, 356-357, 423, 562, 643, 660, 672, 1037, 1169, 1187, 1192
 絕緣層 isolation layer 15, 56-57, 62, 64, 68, 70, 77, 102-103, 119, 222, 346, 348, 350-351, 355, 387, 643, 651, 760, 790, 835, 1172, 1259
 虛擬原型 virtual prototyping 1051
 量子效率 quantum effect 571
 量子電漿波光子學 plasmonic photonics 946
 量規因子 gauge factor 80, 343, 470, 477, 716
 開迴路控制 open-loop control 733-735
 陽極接合 anodic bonding 332, 477, 487, 683, 778, 783, 790, 792, 794-797, 801, 810, 814, 828
 雲霧室 cloud chamber 581-582
 順序法 sequential method 1100

十三劃

圓偏極光干涉光場 circular polarization interferometer configuration 953
 微加工製程 micromachining 4, 7, 54, 75, 78, 97, 101-106, 110-112, 141, 144-146, 159, 211, 272, 322, 344, 350, 355-356, 359, 374, 454, 459, 467, 516, 527, 618, 621, 630, 637, 648, 672, 677, 759, 868, 1054, 1094, 1131, 1141-1142
 微成形 micro molding 4, 143-144, 246-248, 253, 294, 298
 微放電加工 micro electrostatic discharge machining (μ -EDM) 4, 75-77, 144, 254-256, 260, 262, 264, 266, 435, 444-445
 微陀螺儀 microgyroscope 116, 375, 505-513, 515-519, 630, 706, 1087, 1203, 1209-1211
 微型熱交換器 micro heat exchanger 454, 458-459
 微流 micro flow 4, 97-98, 145-146, 177, 202, 221-222, 272-273, 281, 286, 290-294, 296, 306-308, 333-335, 355, 357, 390, 417, 453-454, 460, 471, 535, 537-539, 566, 626, 683-684, 785, 802, 808, 1006-1007, 1013, 1017-1022, 1070, 1077, 1098, 1100-1101, 1120-1121, 1124-1125, 1128, 1130, 1132, 1134-1137, 1139, 1144-1145, 1147, 1150, 1155, 1204, 1208
 微流道 micro channel 4, 145, 177, 221-222, 265, 272-273, 281, 307-308, 417, 453-454, 460, 535, 802, 1017-1019, 1022, 1101, 1121, 1124, 1132, 1135, 1150
 微流體系統 microfluidic system 1017, 1124-1125, 1130, 1132, 1134-1135, 1139
 微流體控制 micro flow control 1134
 微流體開關 micro flow switch 1124, 1134-1136
 微探針 microprobe 141, 254, 417, 449-450, 922
 微接觸印刷 microcontact printing (μ CP) 144, 166, 294, 297-298, 300, 457
 微通道面板 microchannel plate 454, 457
 微揚聲器 microspeaker 376-377, 670, 677
 微開關 microswitch 816, 833-837, 1037, 1162, 1164, 1167, 1173-1174, 1180, 1201
 微雷射光合高分子成形技術 microstereolithography (MSL) 144, 285-286, 288-294

1270

- 微電泳晶片 micro capillary electrophoresis chip (μ -CE) 1144, 1146-1147
- 微閥門 microvalve 97, 141, 168, 308, 357, 385, 390, 659, 684, 1017, 1070, 1124, 1130-1134, 1204
- 微噴嘴 micronozzle 4, 224, 417, 422, 432-434, 436, 446-447, 1017, 1070
- 微熱管 micro heat pipe 454-455
- 微幫浦 micropump 4, 97, 141, 143, 168, 227, 308, 357, 361, 385-387, 390, 1017, 1070, 1124-1130, 1132, 1204
- 微轉印成形 microtransfer molding (μ TM) 144-145, 294, 301, 303
- 感測材料 sensor material 132, 322, 361-362, 366, 368, 370-371, 377, 523, 529, 825
- 感測器封裝 sensor package 498-499, 778-780, 816, 1214
- 感應耦合電漿離子蝕刻 inductively coupled plasma-reactive ion etching (ICP-RIE) 144, 181, 183-184, 210-215, 217-218, 220-225
- 溶膠-凝膠法 sol-gel 246, 358, 380, 388, 683
- 溼潤劑 wetting agent 231, 233, 242
- 準分子雷射 excimer laser 28, 33, 75-77, 144, 146, 185-189, 191-192, 194-196, 200, 203-210, 301, 432, 436, 438, 442, 1146
- 運動感測器 motion sensor 1226, 1228
- 運動解耦 motion decoupling 509, 512-513, 515-516, 518-519
- 雷射干涉儀 laser interferometer 952-953, 973, 978
- 雷射光學尺 laser encoder 960-963, 966, 973, 977
- 雷射共焦掃描顯微儀 laser confocal scanning microscope 996
- 雷射都卜勒流速儀 laser Doppler velocimeter 543-544, 1006-1007, 1022
- 電子束微影 electron beam lithography (EBL) 33, 43-47, 423, 1245, 1247, 1250
- 電子斑點干涉術 electronic speckle pattern interferometry (ESPI) 978-979, 981, 987-988, 995
- 電子微探儀 electron probe micro-analyzer (EPMA) 404
- 電流體 electrorheological fluids 378, 391, 1125, 1129, 1135
- 電胞膜穿孔基因轉殖晶片 micro electroporation chip (μ EP chip) 1148
- 電致伸縮 electrostrictive 378, 381-382, 391
- 電氣沉積 electro-deposition 439
- 電荷耦合元件 charge-coupled device (CCD) 116, 191, 417, 583-585, 663, 764, 944, 1007, 1012, 1016-1017, 1021, 1152
- 電著性 throwing power 232-233, 243
- 電腦輔助工程 computer-aided engineering (CAE) 1051-1052
- 電磁式微致動器 electromagnetic actuator 229, 614, 670
- 電漿子 plasmon 996, 1000-1006
- 電漿輔助化學氣相沉積 plasma-enhanced chemical vapor deposition (PECVD) 31, 68-70, 104, 125, 221, 269, 282, 343, 346, 348, 354, 562, 1169
- 電熱式微致動器 electrothermal actuator 614, 657-658
- 電橋電路 deflection bridge circuit 712-718, 730
- 電鍍 electroplating 103, 110, 113, 121, 131, 143, 151, 154, 158, 225, 227-228, 239, 242-243, 254-256, 276, 306, 345, 347, 356-357, 378, 393-394, 396, 399-401, 439, 445, 502, 670, 672, 674-675, 677, 835, 1037, 1096, 1179, 1183
- 電轉殖 electroporation (EP) 19, 50, 56, 78, 101, 114, 117, 141, 145, 183, 224, 277, 296, 329, 337, 361, 394, 398, 419, 425, 521, 523, 529, 555, 572, 651, 737, 775, 794, 844, 911, 932, 934, 986, 1005, 1037, 1072, 1096,

1128, 1148-1150, 1174

電鑄 electroforming 4, 75, 77, 143-145, 151-152, 156-157, 171-172, 175-176, 178-180, 183-185, 192, 203-204, 210, 224-246, 255, 361, 426, 428, 434-435, 439, 442-445, 453, 519, 1094, 1097, 1179, 1183

預置擴散 predeposition diffusion 9-10, 20

十四劃

圖形使用者介面 graphic user interface (GUI) 1051

圖案轉移 pattern transfer 33, 48, 226, 1247

寡核苷酸晶片 oligonucleotide chip 1118

對位公差 alignment tolerance 961, 963, 965-966, 977

對準 alignment 25, 36-37, 78, 89, 113-114, 141, 154, 158, 162-163, 173, 185, 203, 206, 218, 322, 330, 420, 428, 472, 484, 503, 519, 598, 637, 695, 789, 801, 814, 818-820, 835, 955, 961, 1055, 1095, 1146, 1253

摻雜濃度 dopant concentration 14-15, 95, 141, 331, 407, 474, 496, 584, 906, 1095

磁力顯微術 magnetic force microscopy 450-451, 901, 903

磁共振力顯微鏡 magnetic resonance force microscope (MRFM) 1256-1257

磁致伸縮 magnetostrictive 362, 378-379, 383-384, 391, 674

網格 mesh 276, 483, 491, 777, 823, 1054-1055, 1057, 1070, 1096-1098, 1100-1101

聚甲基丙烯酸酯 polymethylmethacry (PMMA) 77, 149-153, 156-161, 163-164, 186, 194-196, 200, 203, 264, 296, 306, 336, 357, 430-432, 441, 801, 959, 1146, 1247, 1252

聚合化 polymerized 418

聚合酶連鎖反應 polymerase chain reaction (PCR) 1118, 1139-1144, 1156, 1218-1219

聚苯乙烯 polystyrene (PS) 4, 17, 76, 105, 120, 131, 180, 306, 336, 372, 388, 422, 460, 507, 525-526, 578, 580, 614, 619, 629-632, 655, 666-667, 710, 719, 751, 759, 775-776, 909, 931, 1097-1098, 1111, 1141, 1146, 1161-1163

聚對二甲苯 parylene 77, 145, 271-274, 281-282, 551

蓋格計數器 Geiger counter 581

蒸鍍 evaporation 56-61, 63-64, 110, 224, 231, 337, 356, 379, 423, 450, 795, 824, 864, 1247-1250, 1254

蝕刻率 etching rate 81, 91-92, 141, 815, 1080, 1095-1096

裸晶封裝 die packing 769, 785

製程幾何模擬 process geometric simulation 1096

製程階層 process level 1052, 1054, 1083, 1085

製程模擬 process simulation 1052, 1054-1055, 1083, 1094-1098

十五劃

撓性共振器 flexural resonator 1247, 1249

數位光學處理技術 digital light processing (DLP) 211, 1108, 1227

數位-類比轉換 digital to analog conversion (DAC) 721, 724-725, 730

數值孔徑 numerical aperture (NA) 4, 81-82, 102, 121, 150, 191, 194-195, 201, 275, 281, 330-331, 383, 387, 417-419, 427, 452-453, 792-793, 845, 889, 936, 938-940, 969, 972, 998-999, 1007, 1012, 1117-1120, 1139, 1144, 1146-1151, 1153-1157, 1159, 1167, 1201, 1218-1220, 1223

- 數學模型 mathematical model 2, 974, 1050, 1052, 1056, 1091, 1100
- 暫態彈性波 transient elastic wave 1212-1214
- 暫態響應 transient response 571, 578, 580, 732, 737-738, 740, 744, 747, 750
- 模糊控制 fuzzy control 757-758
- 槳形振盪器 paddle oscillator 1250
- 歐傑電子光譜 Auger electron spectroscopy (AES) 401, 406, 584, 1005
- 熱光伏 thermal photovoltaic (TPV) 462
- 熱式流量感測器 thermal flow sensor 532, 540-541
- 熱固性 thermosetting 335, 398
- 熱阻型微輻射感測器 microbolometer 524
- 熱性感測器 thermal detector 523, 527
- 熱氧化 thermal oxidation 7, 15, 19, 28, 32, 66, 331, 337, 344-346, 348, 351, 355-356, 358, 864
- 熱塑性 thermoplastic 275, 335, 398
- 熱線型流速計 hot wire anemometer 532-538
- 熱機械等效雜訊 thermomechanical noise 708
- 熱膨脹係數 coefficient of thermal expansion (CTE) 35, 79-80, 112, 141, 229, 332, 338, 363, 377-378, 390, 392, 397, 399, 401, 454, 477, 487-490, 500, 502, 519, 564, 658-661, 666, 693, 778, 783, 792, 794-795, 805, 864, 866, 883, 974, 1037-1038, 1065, 1127, 1134-1135
- 熱壓法 hot embossing 226, 246-247, 429-430
- 線性非時變系統 linear time invariant (LTI) 4, 76, 105, 128, 166, 174, 201, 268, 397, 405, 425, 490, 614, 633, 737-738, 759, 934, 1052, 1084, 1174
- 線性速率係數 linear rate coefficient 18-19
- 緩衝氧化蝕刻 buffered oxide etch (BOE) 284, 332, 346, 352, 356, 358, 1146
- 耦合分析 coupling analysis 1053, 1059, 1100
- 耦合領域模擬 coupled field simulation 1100
- 複合電鑄 composite electroforming 227-228, 240-242
- 複製成形 replica molding (REM) 145, 294, 305-309, 722, 742, 1095
- 調控網路 regulatory network 1119
- 質量流量計 mass flow meter 538-540
- 質傳極限 mass transport limitations 234
- 質體 DNA plasmid DNA 1150-1151
- 輥壓 rolling 246, 249-250
- 駐極體 electret 370, 544, 553-557, 561

十六劃

- 導電層 conductive layer 102, 151, 158, 177, 220, 222, 237, 276, 636, 1253
- 橢圓角 ellipsometric angles 848-849
- 橢圓偏光儀 ellipsometry 19, 68, 847-848, 996
- 積分球分析儀 integrating sphere analyzer 845
- 親和性感測器 affinity sensor 1224
- 輻射極限 radiation-limited 528

霍爾效應 Hall effect 12-13, 116, 588, 590-591, 841
 靜電式微致動器 electrostatically actuator 614, 774
 頻率匹配 frequency matching 509-510, 512-513, 515-516, 519

十七劃

壓力感測器 pressure sensor 98, 101, 118, 123-125, 141, 329, 350, 354, 359-361, 467-469, 471, 475, 477, 480, 488, 494, 496, 498-504, 545, 550, 777-780, 784, 787-789, 796, 804, 823, 825, 827-828, 830, 1022-1023, 1028-1029, 1034
 壓電式微致動器 piezoelectric actuator 614, 678, 681-683, 685-686, 690
 壓應力 compressive stress 95, 111, 247, 331, 340, 343, 346, 358, 390, 489-490, 562, 864, 866, 868, 871-873, 875, 878, 880, 882
 壓縮成形 compression molding 248, 398
 應用層 application layer 102, 119, 124, 931
 檢測技術 measurement technology 503, 841, 867, 883, 886, 918, 946, 952, 960, 978, 995-996, 1006, 1022, 1120, 1225
 檢測度 detectivity 373, 521, 572
 環氧樹脂 epoxy 38, 151, 173, 281, 296, 306, 336, 398, 477, 786, 801, 812, 836, 1214
 磷矽玻璃 phosphosilicate glass (PSG) 50, 68, 103-105, 110, 269, 345-346, 350, 359, 530, 760
 總積分散射光 total integrated scatter (TIS) 845
 聲束成形 beam forming 567
 薄膜體型聲波共振器 thin film bulk acoustic resonator (FBAR) 1191-1192
 黏接接合法 adhesive bonding 790, 802
 黏晶 die attach 398, 477, 778, 783, 812
 點散佈函數 point spread function 997-998

十八劃

擴散 diffusion 7-16, 18-21, 27-28, 30-33, 53, 56-59, 61, 66-68, 233-235, 240-241, 276, 287, 331, 337-338, 341-343, 345, 354, 366, 370-371, 394, 397, 405, 437, 458-459, 471, 477, 538-540, 557, 571, 612, 643, 682, 693, 780-781, 793, 795-796, 798, 801, 806, 808-809, 826, 843, 1019, 1029-1030, 1073, 1083, 1095, 1128, 1144
 擴散控制區域 diffusion-limit region 337
 濾波器 filter 120-121, 125, 160, 209, 289-290, 334, 352, 360, 503, 630, 711, 751-753, 777, 979, 981, 988, 1016, 1022, 1057, 1107, 1114, 1161-1163, 1167, 1175, 1180-1181, 1183-1185, 1187-1188, 1190-1196, 1198-1201, 1214
 濺鍍 sputtering 54-56, 59, 61-64, 70-71, 99, 102, 107-108, 110, 152, 224, 231-232, 274, 331, 337, 341, 344-345, 354, 356-358, 378-379, 383, 390-391, 409, 529-530, 674, 683, 795, 853, 864, 880, 1126
 繞射公差 diffraction grating 961
 繞射式微鏡片 diffractive microlens 417, 423, 428
 覆晶; 覆晶接合 flip chip 77, 394, 396, 399-400, 564, 777, 780-781, 790, 813-814, 816-817, 820, 1182, 1197
 轉式步進馬達 rotary stepper motor 668
 轉移成形 transfer molding 398, 477

1274

轉換函數 transfer function 127, 707, 734-736, 738-739, 743, 745-747, 749, 751-754, 757, 775
鎢晶格 tungsten lattice 460, 462
鎢燈泡 cool tungsten bulb 460, 462
離子佈植 ion implantation 7, 20-21, 24, 30, 117, 331, 342, 530, 826, 1252
離子束磨削 ion beam milling 49-50, 329
雜合反應 hybridization 1117-1118, 1154
鬆弛法 relaxation method 1058-1059, 1100

十九劃

曝光劑量 exposure dose 149-150, 161-162, 164, 166, 173, 175, 177, 179, 182, 203, 425
穩態響應 steady-state response 740
邊界元素法 boundary element method 1051, 1053-1054, 1056-1058, 1081, 1099-1100
邊緣電場效應 fringe effect 628, 635
類比－數位轉換 analog to digital conversion (ADC) 10, 623, 721, 725-730, 751, 782, 828, 1171

二十劃

觸發時間原點 initiation time origin 1213

二十一劃

犧牲層 sacrificial layer 3, 77-78, 97-99, 101-105, 107-109, 112, 118, 125, 130, 141, 211, 255, 269, 271-274, 276, 281-282, 306, 322, 336, 342-346, 350-352, 354-360, 529, 535, 555, 562, 565, 617-621, 643, 645, 660, 672, 760, 816, 831, 835, 1096, 1169, 1171, 1179, 1183, 1188, 1192
鐵氟龍 Teflon 141, 143, 145, 167, 241, 271, 284, 555-556, 561
鐵磁性形狀記憶合金 ferromagnetic shape memory alloy (FMSMA) 391
響應度 responsivity 372, 521-522, 525-527, 529, 571-572, 575-576, 578
驅入擴散 drive in diffusion 10
彎曲平板波 flexural plate wave (FPW) 368, 386

二十二劃

疊紋干涉術 moiré interferometry 960, 969, 974, 976, 978

二十三劃

體型微加工 bulk micromachining 75-80, 91-92, 95, 97, 101, 110, 116-117, 144, 322, 329, 331, 347, 354-355, 360, 454, 459, 476, 550, 555, 618, 621, 868, 1094-1095, 1131, 1247
體積對表面積比 volume to surface ratio 1141-1142